

mirao™ 52-e

Electromagnetic Deformable Mirror

Technical Specifications

mirao's patented technology, plug-n-play installation, built-in protection (voltage clipping/temperature) and powerful API for C/C++ programmers make it the ideal choice for researchers developing innovative ophthalmic applications using adaptive optics. Even more, mirao is optimized to function with our HASO™4 first wavefront sensors and WaveTune™ control software.

Package contents:

- deformable mirror
- plug-n-play electronic control unit and connection cables
- CD-ROM: mirao 52-e API & examples and demo application

± 50 µm

user manual

Main specifications

Number of actuators

Maximum generated wavefront (PV) Surface quality (RMS active flat)

Wavefront quality (RMS active flat)

Integrated tip/tilt correction Spatial frequency correction

Effective diameter

Linearity

Hysteresis Actuator input voltage

Coatings

Power consumption

Dimensions / weight (mirror unit only)

Connectivity / Compatibility

52

50 µm (tilt)

0.01 µm

 $0.02 \, \mu m$

Yes

Zernike orders up to 6

15 mm

> 95%

< 2%

±1V max in each of the 52 channels

Sum of absolute voltages < 25 V

Protected silver

50 W max.

64 x 64 x 23 mm / 490 a

USB 2.0 / Windows® XP, 7 (x32)

± 50 µm

Zernike order

Maximum peak-to-valley (PV) wavefront generation

± 30 µm ± 35 µm ± 30 µm ± 10 µm ± 10 µm ± 25 µm

Zernike mode quality:

RMS residual wavefront error: max 0.020 µm

(generation of any Zernike mode of order <5 with an amplitude set at 20% of total dynamic range)

